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(71) Applicant: **ACM RESEARCH (SHANGHAI) INC.** [CN/CN]; Bld. 4, No. 1690 Cailun Road, Zhangjiang High-tech Park, Shanghai 201203 (CN).

(72) Inventors: **WANG, Hui**; Bld. 4, No. 1690 Cailun Road, Zhangjiang High-tech Park, Shanghai 201203 (CN). **CHEN, Fuping**; Bld. 4, No. 1690 Cailun Road, Zhangjiang High-tech Park, Shanghai 201203 (CN). **ZHANG, Huaidong**; Bld. 4, No. 1690 Cailun Road, Zhangjiang High-tech Park, Shanghai 201203 (CN). **WANG, Wenjun**; Bld. 4, No. 1690 Cailun Road, Zhangjiang High-tech Park, Shanghai 201203 (CN).

(74) Agent: **SHANGHAI PATENT & TRADEMARK LAW OFFICE, LLC**; 435 Guiping Road, Shanghai 200233 (CN).

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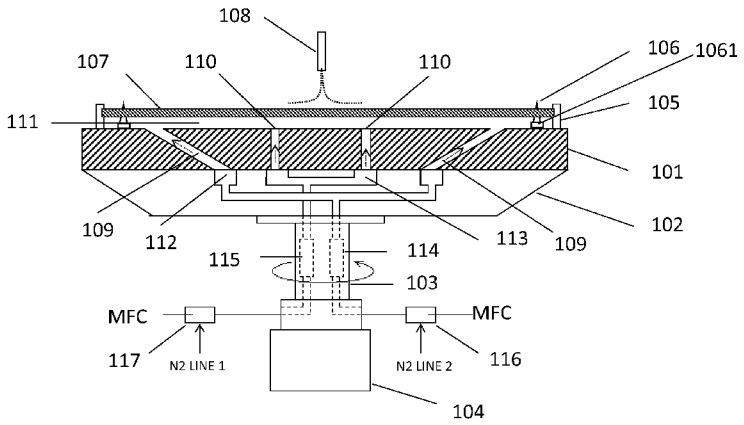


FIG 1

(57) Abstract: The present invention provides a substrate supporting apparatus having a rotatable chuck, a first mass flow controller, a second mass flow controller, a plurality of locating pins and guiding pillars, and a motor. The rotatable chuck for supporting a substrate defines a plurality of first injecting ports and second injecting ports. The first injecting ports are connected with a first gas passage for supplying gas to the substrate and sucking the substrate by Bernoulli effect. The second injecting ports are connected with a second gas passage for supplying gas to the substrate and lifting the substrate. The first mass flow controller and the second mass flow controller are respectively installed on the first gas passage and the second gas passage. The plurality of locating pins and guiding pillars are disposed at the top surface of the rotatable chuck and every guiding pillar protrudes to form a holding portion. The motor is used for rotating the rotatable chuck.

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